

Notice of References Cited

Application/Control No.

10/581,633

Applicant(s)/Patent Under
Reexamination
SHIMA ET AL.

Examiner

ANNA L. VERDERAME

Art Unit

1795

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B	US-5,401,609	03-1995	Haratani et al.	430/270.12
	C	US-			
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	I	US-			
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	M	US-			

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	N	JP-09-296266	11-1997	Japan	Shimizu et al.	
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	U	Salama. RF Sputtered Aluminum Oxide Films on Silicon. Toronto University Department of Electrical Engineering(1970).
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.